

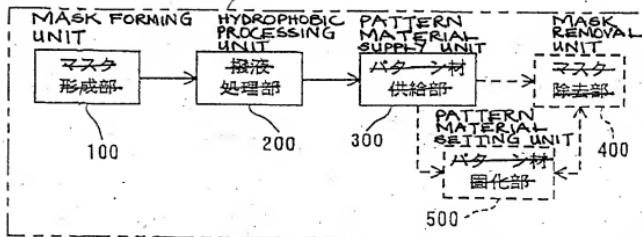
FIG.  
図 1PATTERN FORMING APPARATUS  
10 パターン形成装置

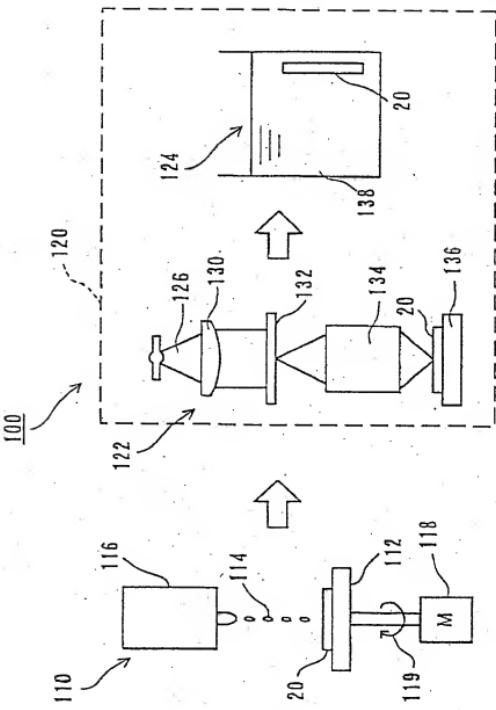
FIG.  
2

FIG. 3

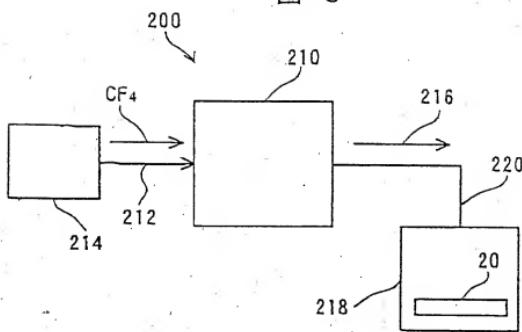


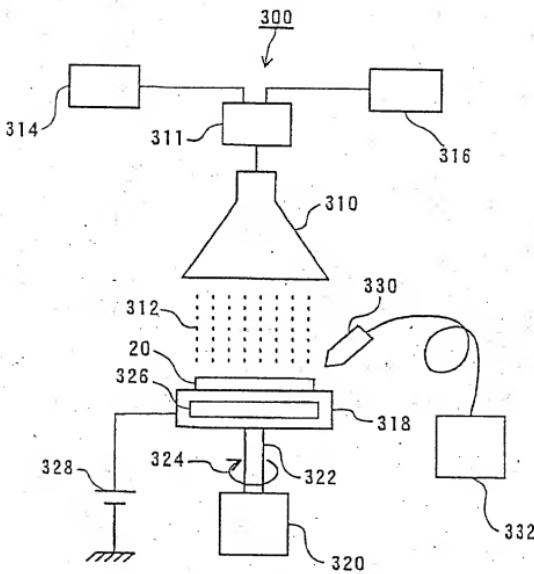
FIG.  
4

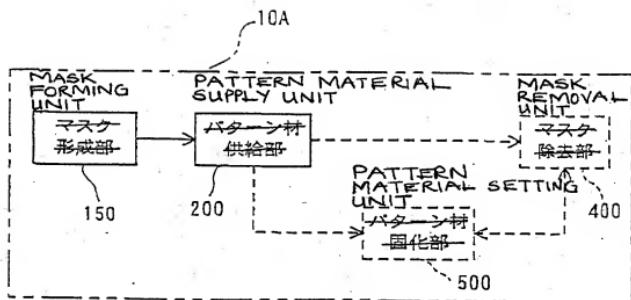
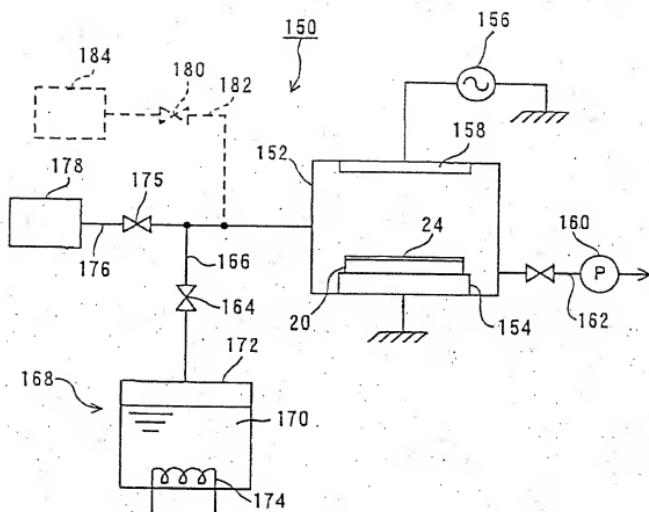
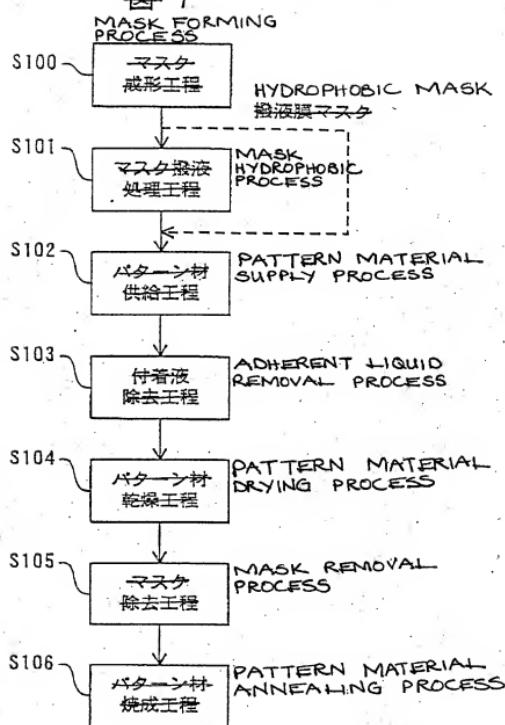
FIG.  
図 5

FIG.  
6

K00262666-042020

FIG.

图 7



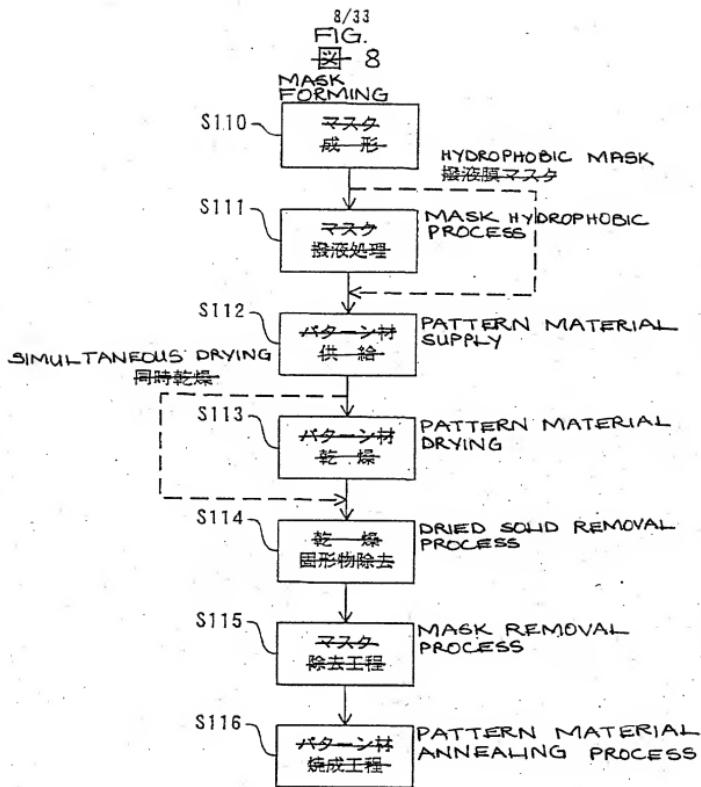
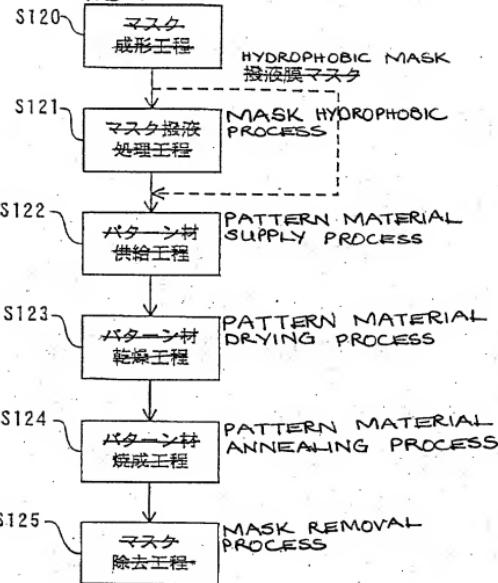


FIG.

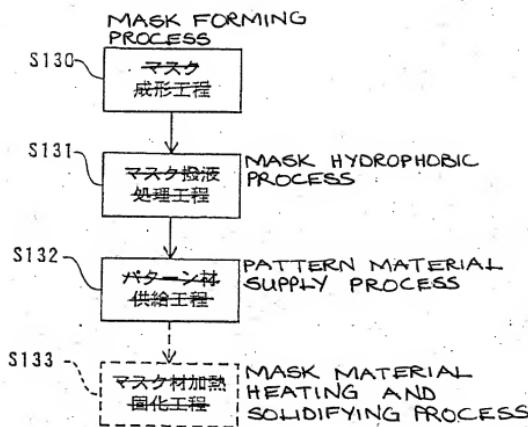
图 9

MASK FORMING  
PROCESS

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FIG.

図 10



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FIG.

図 11

MASK FORMING  
PROCESS

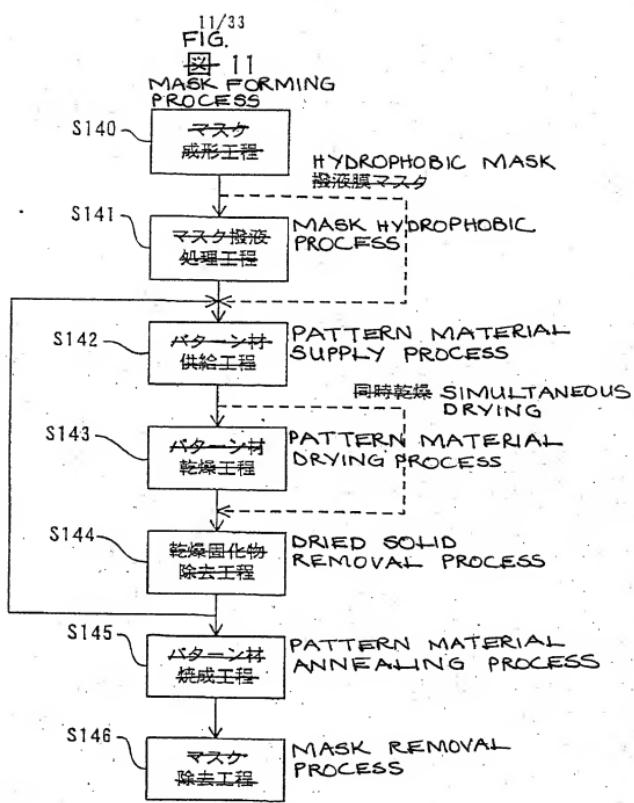


FIG.

図 12

## MASK FORMING PROCESS

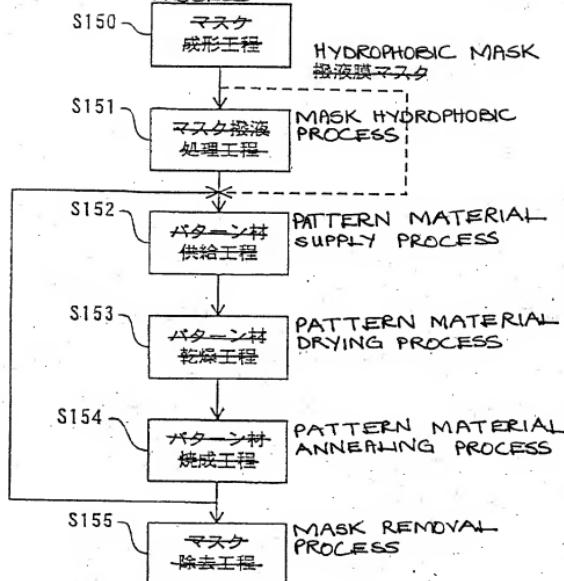


FIG.

13

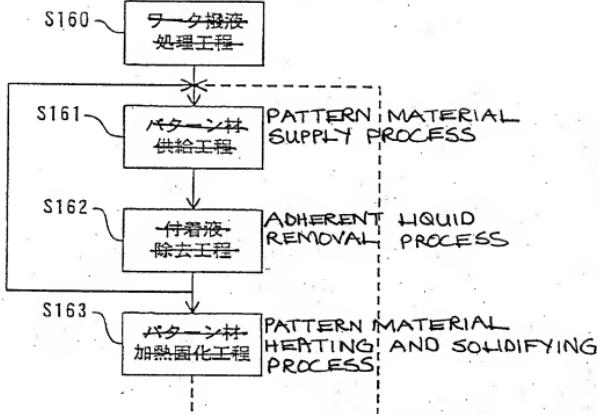
WORKPIECE HYDROPHOBIC  
PROCESS

FIG.

14

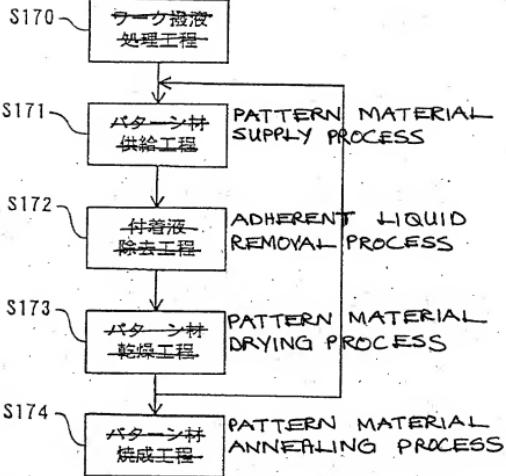
WORKPIECE HYDROPHOBIC  
PROCESS

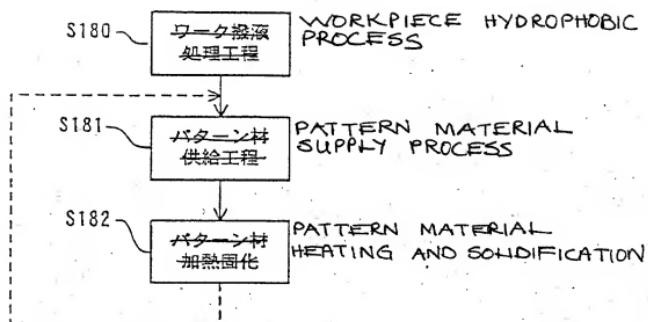
FIG.  
図 15

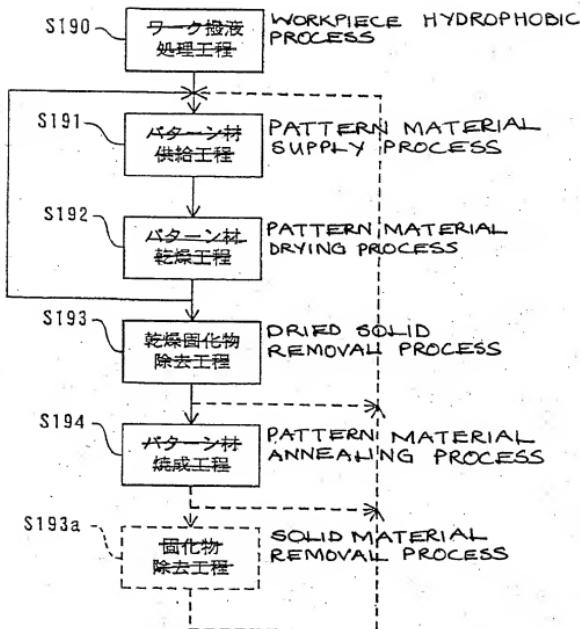
FIG.  
図 16

FIG.

図 17

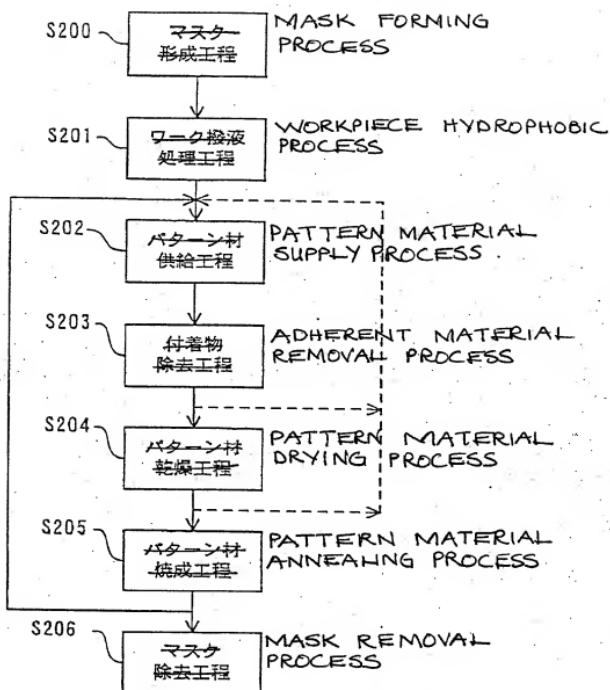
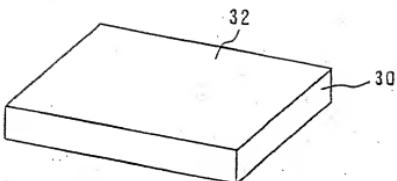
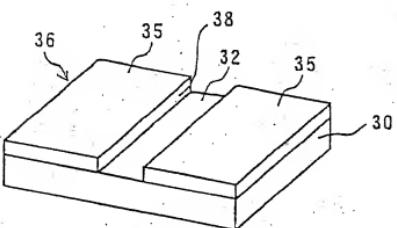


FIG.  
図-18

(1)



(2)



(3)

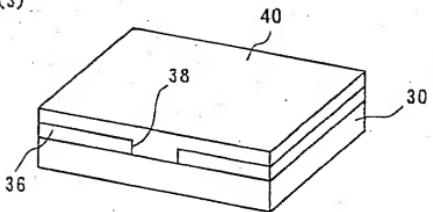
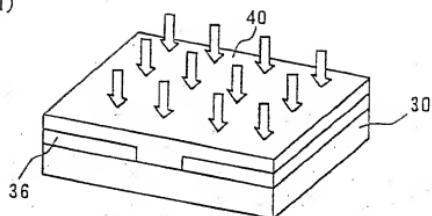
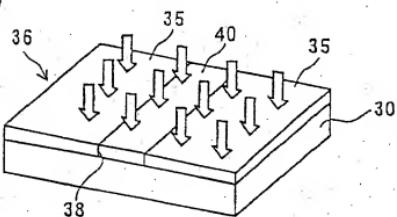


FIG.  
- 19

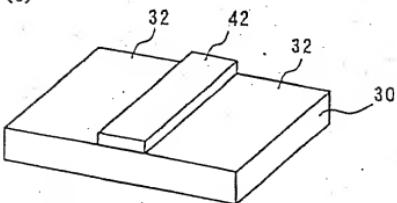
(1)

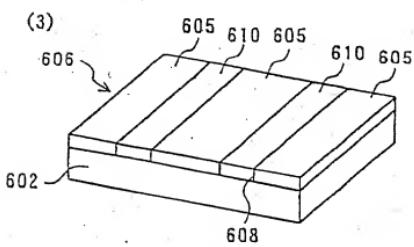
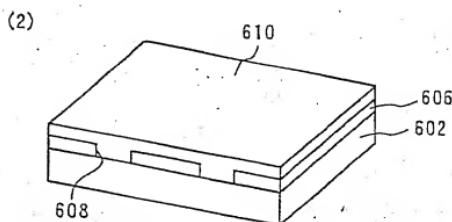
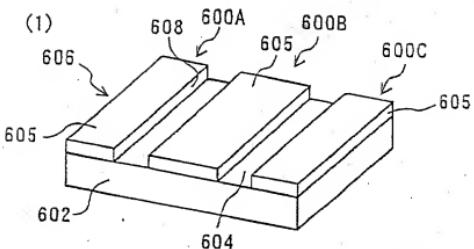


(2)



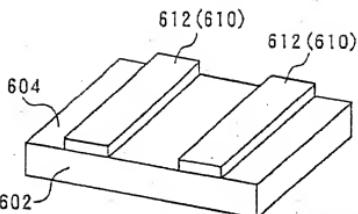
(3)



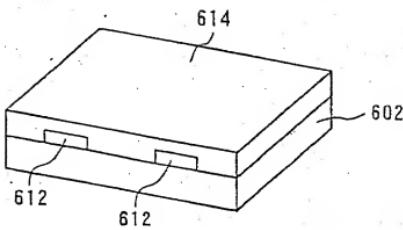


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FIG.  
- 21

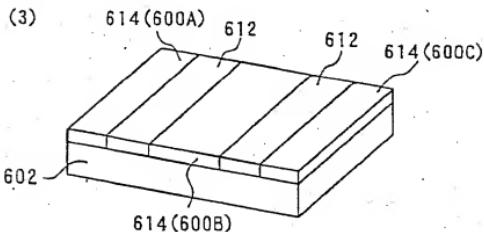
(1)



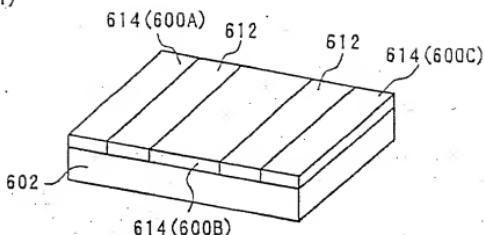
(2)



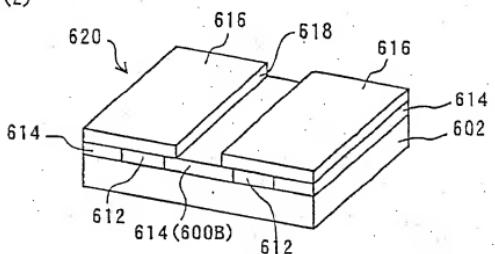
(3)



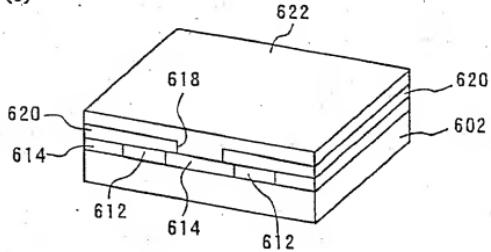
(1)



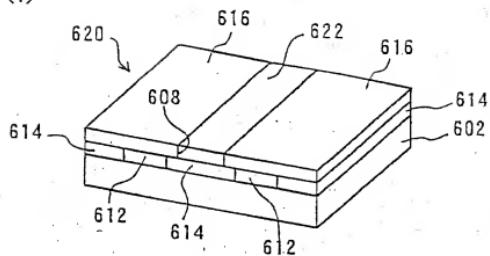
(2)



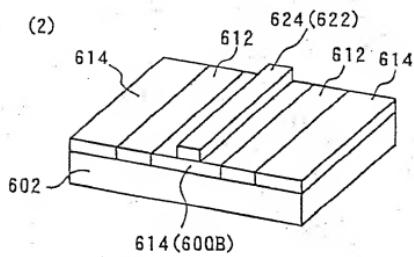
(3)



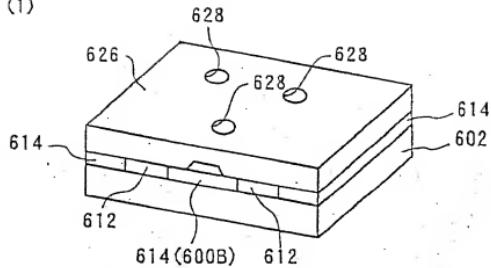
(1)



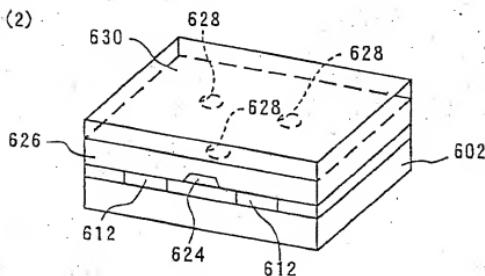
(2)



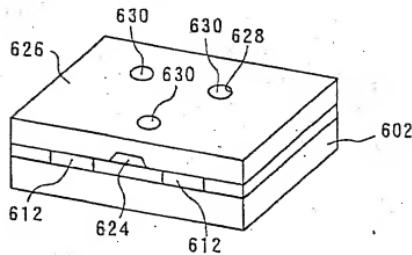
(1)



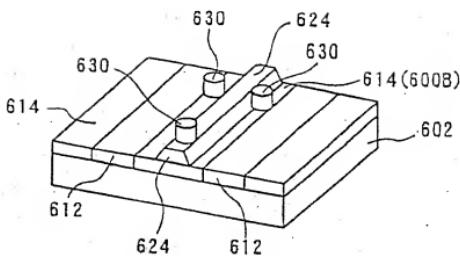
(2)



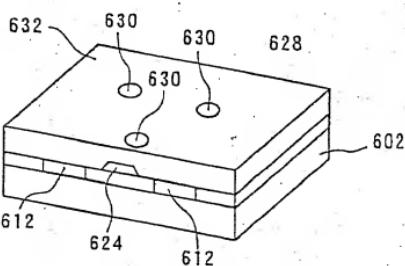
(3)



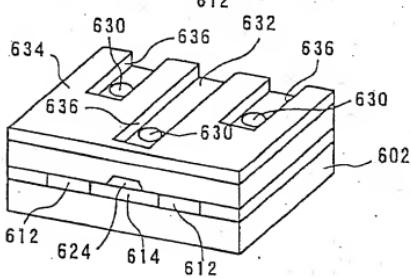
(1)

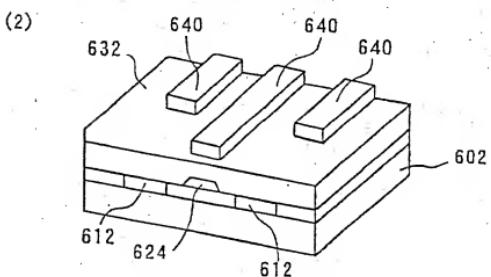
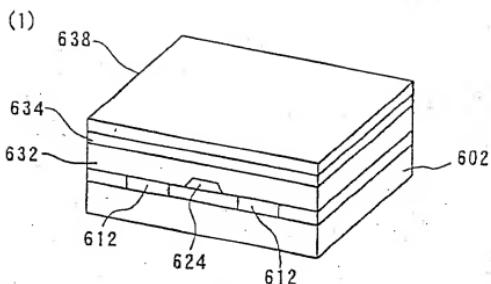


(2)



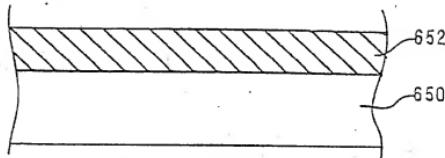
(3)



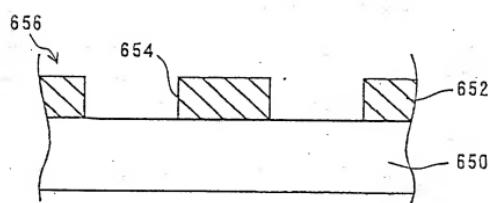


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FIG.  
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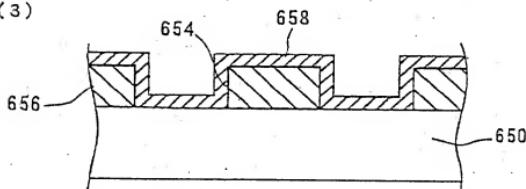
(1)



(2)



(3)



(4)

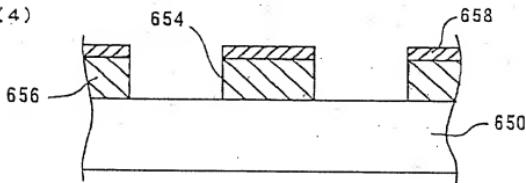


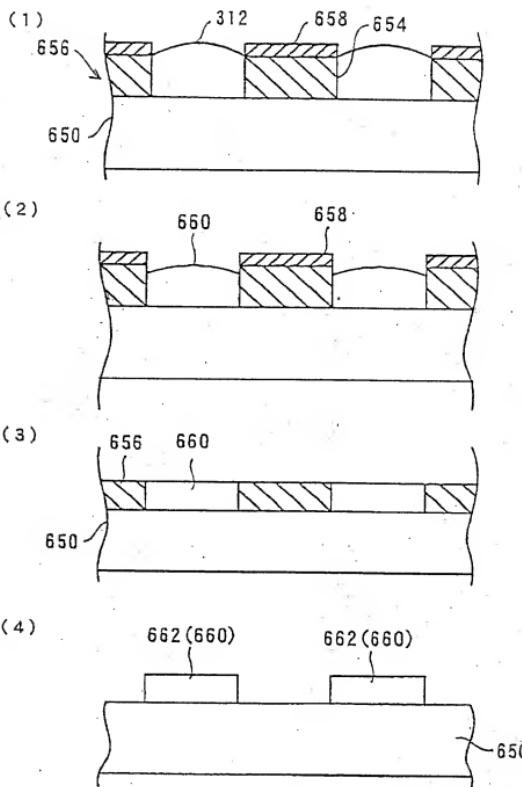
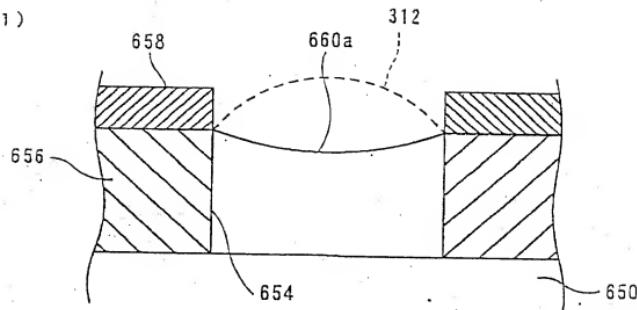
FIG.  
28

FIG.  
29

(1)



(2)

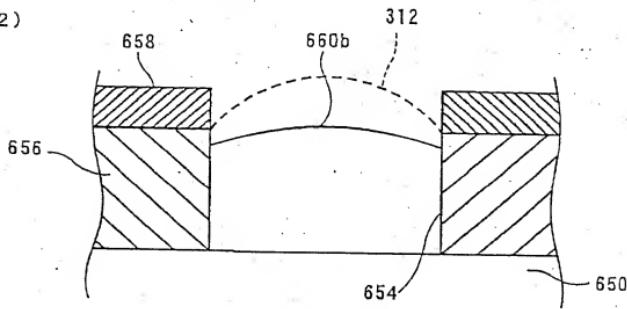


FIG.  
図 30

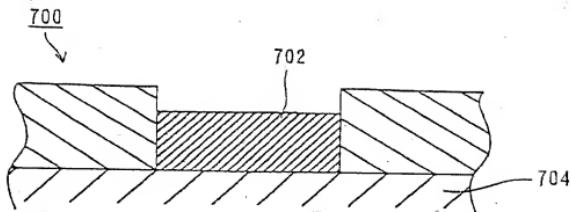
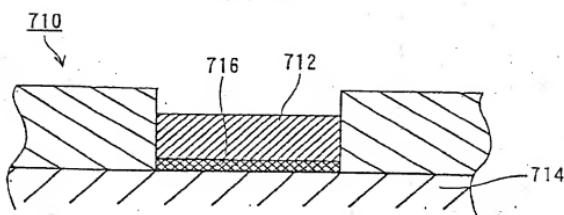


FIG.  
図 31



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FIG.  
图 32

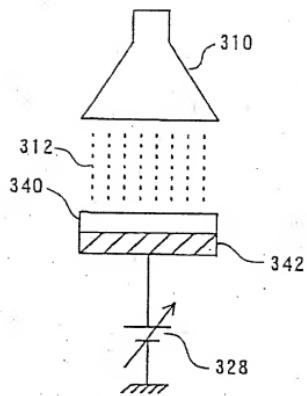
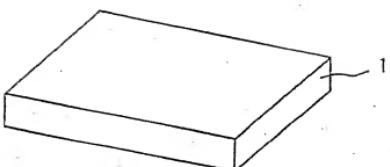
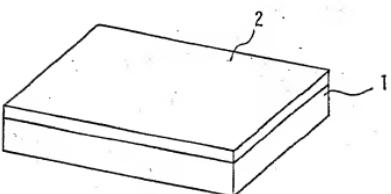


FIG.  
33

(1)



(2)



(3)

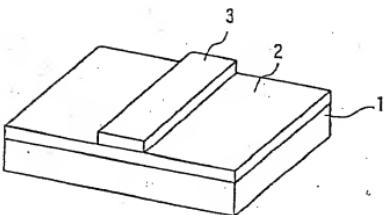
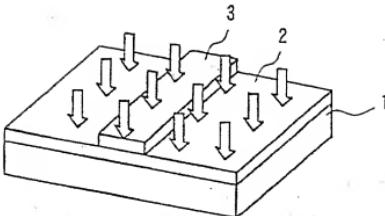
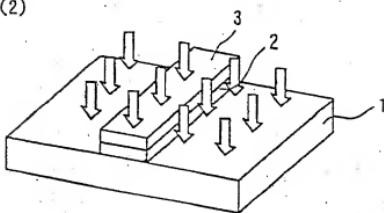


FIG.  
34

(1)



(2)



(3)

